

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of	Confirmation No.: 5877
Kenichi MORIMOTO	Art Unit: 1763
S. N. 10/737,393	Examiner: Allan W. Olsen
Filed: December 16, 2003	

For: MASK BLANK FOR CHARGED PARTICLE BEAM EXPOSURE, METHOD OF
FORMING MASK BLANK AND MASK FOR CHARGED PARTICLE BEAM EXPOSURE

RESPONSE TO OFFICE ACTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the office action dated December 14, 2005,
for which a three month extension of time is requested to extend
the period for response to June 14, 2006, please make the
following amendments:

Claim amendments begin on page 2 of this document.

Remarks begin on page 4 of this document.